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## BIB DATA SHEET

CONFIRMATION NO. 1704

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.		
10/550,897	09/27/2005	438	2822	Q90606		
<b>RULE</b>						
<b>APPLICANTS</b> Akira Kobayashi, Yokohama, JAPAN; Tsunehisa Namiki, Yokohama, JAPAN; Hiroko Hosono, Yokohama, JAPAN; Hideo Kurashima, Yokohama, JAPAN; Hajime Inagaki, Yokohama, JAPAN; Toshihide Ieki, Yokohama, JAPAN;						
<b>** CONTINUING DATA *****</b> This application is a 371 of PCT/JP04/03992 03/23/2004						
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 2003-092265 03/28/2003 JAPAN 2003-206714 08/08/2003						
<b>** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **</b> 08/14/2006						
Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Verified and Acknowledged <u>/KEVIN M PICARDAT/</u> Examiner's Signature		<input type="checkbox"/> Met after Allowance Initials	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWINGS</b> 8	<b>TOTAL CLAIMS</b> 14	<b>INDEPENDENT CLAIMS</b> 2
<b>ADDRESS</b> SUGHRUE MION, PLLC 2100 PENNSYLVANIA AVENUE, N.W. SUITE 800 WASHINGTON, DC 20037 UNITED STATES						
<b>TITLE</b> Chemical vapor deposited film based on a plasma cvd method and method of forming the film						
<b>FILING FEE RECEIVED</b> 900	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:			<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		